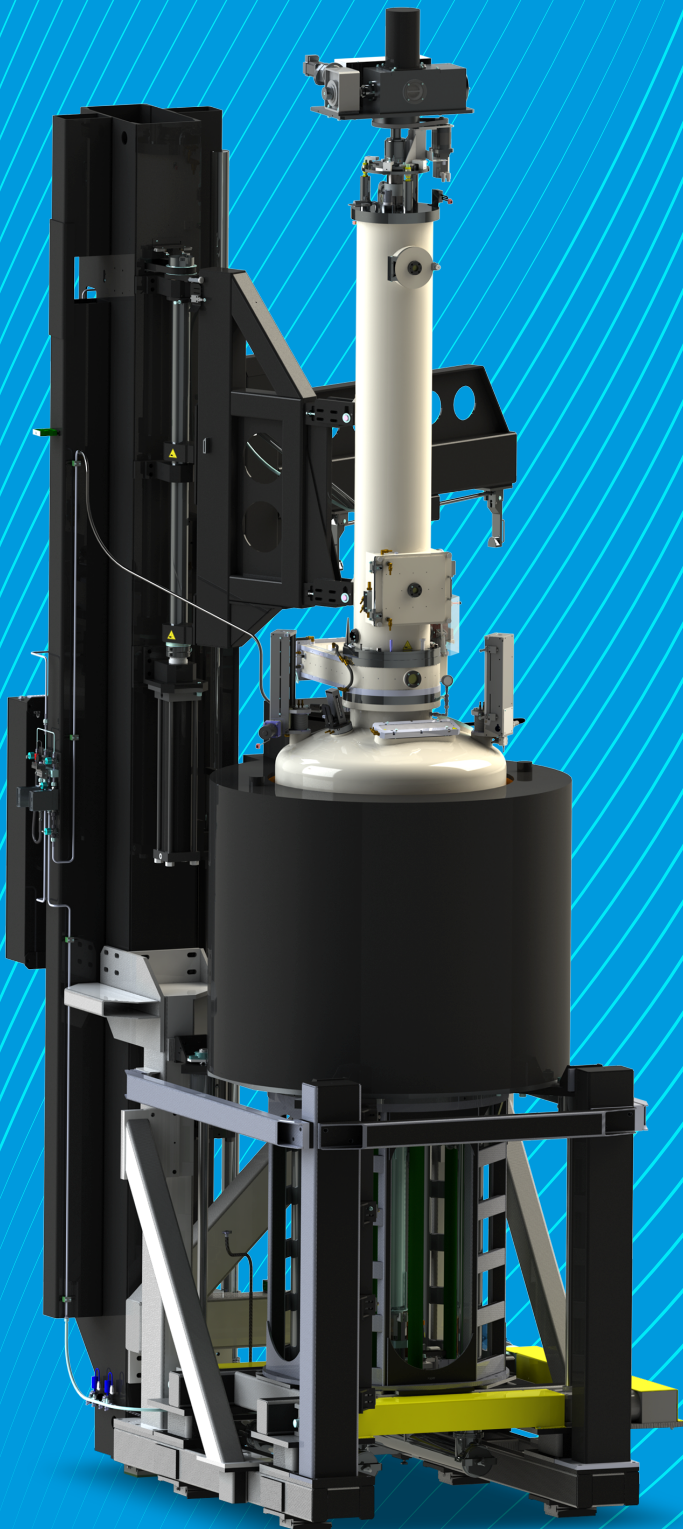


# Linton



## KX320 MCZR

Semiconductor Crystal Growing Furnace

- Optimized For 300 mm Ingot Growth
- 4000 Gauss Superconducting Magnet
- Advanced Control System
- Low Power Consumption
- Integrated Communications with optional WINGS system
- Complete Customization Available



# KX320MCZR

## Semiconductor Crystal Growing Furnace

The KX320MCZR is optimized for producing 300 mm crystals with a 1300 mm furnace size and 3500 mm-high receiving chamber for accommodating 32-inch crucibles and is magnet-ready. Options include resistive and superconducting magnets.

### PERFORMANCE

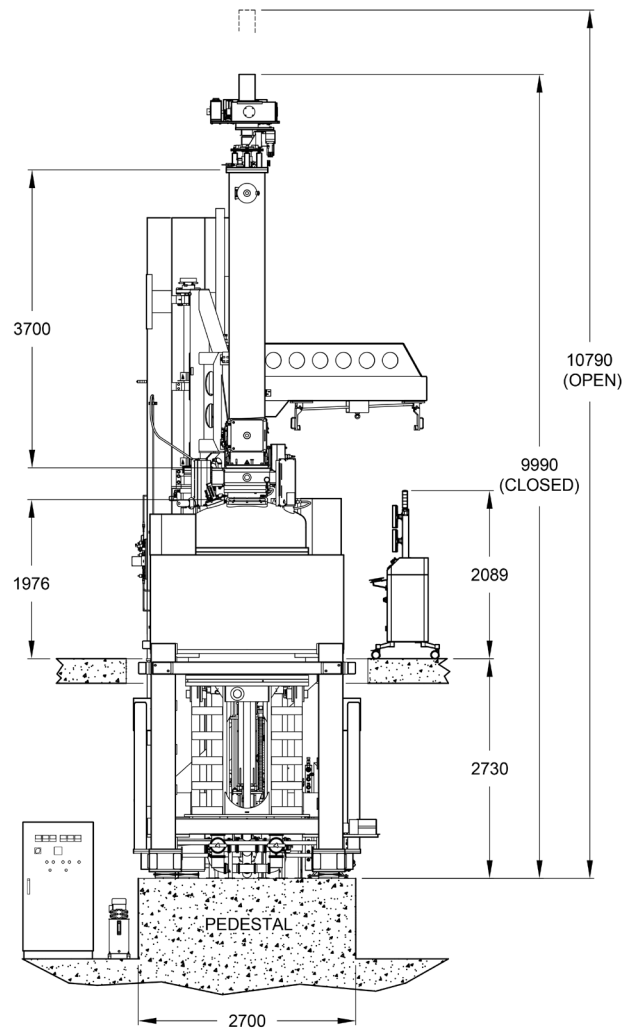
Furnace Chamber Diameter	1275 mm (50.2 in)
Receiving Chamber Height	3700 mm (145.6 in)
Throat Diameter	400 mm (15.7 in)
Seed Lift Rate	0-508 mm/hr
Seed Jog Speed (Nominal)	400 mm/min
Seed Rotation (Reversible)	0-20 rpm
Total Crucible Travel	850mm (33.5 in)
Crucible Lift Rate	0-127 mm/hr
Crucible Jog Speed (Nominal)	127 mm/min
Crucible Rotation (Reversible)	0-12 rpm

### SILICON CHARGE CAPACITY

CRUCIBLE DIAMETER	CHARGE SIZE
32.0 in	up to 440 kg

### OPTIONS & ACCESSORIES

Cooling Tube	Cusp Magnet
Feeders	Vacuum Pumps
Hot Zones	Ingot and Crucible Handling
Filters	Maintenance Tools



Dimensions shown are typical and can be customized to meet customer requirements